



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **WATANABE, Kenichi**

Group Art Unit: **2815**

Serial No.: **09/987,012**

Examiner: **Chris C. Chu**

Filed: **November 13, 2001**

**P.T.O. Confirmation No.: 6363**

For: **SEMICONDUCTOR WAFER DEVICE HAVING SEPARATED CONDUCTIVE PATTERNS IN PERIPHERAL AREA AND ITS MANUFACTURING METHOD**

**RESPONSE UNDER 37 CFR §1.116**  
**- EXPEDITED RESPONSE -**  
**GROUP ART UNIT 2815**

**MAILSTOP AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

November 12, 2003

Sir:

In response to the Office Action dated **August 1, 2003**, extended to **December 1, 2003** by a **one (1)** month Petition for Extension of Time, please amend the above-identified application as follows:

RECEIVED  
NOV 25 2003  
TECHNOLOGY CENTER 2800